

Docket No.: SON-2413/DIV
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Shigeru Moriya, et al.

Application No.: Not Yet Assigned

Art Unit: 2814

Filed: Concurrently Herewith

Examiner: T. Le

For: MASK, METHOD OF PRODUCING MASK,
AND METHOD OF PRODUCING
SEMICONDUCTOR DEVICE

FIRST PRELIMINARY AMENDMENT

MS Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.